

# Microbolometer matrices development at russian federation state scientific centre "Orion"

*S. Ya. Andryushin, N. V. Kravchenko, A. V. Kulymanov,  
G. V. Liberova, I. I. Taubkin, M. A. Trishenkov,  
A. M. Filachov, Yu. M. Eskin*

State Unitary Enterprise «RD&P Centre "Orion"», Moscow, Russia

*State and perspectives of microbolometer matrices development at State Scientific Centre "Orion" are discussed. Information on carried out microbolometer matrix (MBM) of 64x64 format is presented. Microbolometer element design, MBM electric layout, technology features and bolometer layer parameters values are described. Microbolometer structure spectral sensitivity range belongs to ~9,1 through 14,5  $\mu\text{m}$  wavelength band, thermal time constant is ~ 5 through 20 ms, and noise equivalent temperature difference (NETD) value is estimated as 0,3 K. The further works on MBMs development to be carried out at "Orion" are announced.*

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